

ABSTRACT

MASK HANDLING APPARATUS, LITHOGRAPHIC PROJECTION APPARATUS,
DEVICE MANUFACTURING METHOD AND DEVICE MANUFACTURED THEREBY

In a lithographic projection apparatus, an object such as a mask is shielded from stray particles by a particle shield using electromagnetic fields. The fields may be a uniform electric field, a non-uniform electric field or an optical breeze. The particle shield is fixed to the mask holder rather than the mask.

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